Amendments To Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Original) A substrate cutting system, comprising:

a pair of scribing line forming means arranged facing each other;

a pair of scribing devices for supporting the pair of scribing forming line means such that one of the pair of scribing forming line means moves on a first surface of a substrate in an X axial direction and the other of the pair of scribing forming means moves on a second surface of the substrate in the X axial direction;

a scribing device guide body for supporting the pair of scribing devices such that the pair of scribing devices moves in a Y axial direction; and

a substrate supporting means for supporting the substrate in an X-Y plane such that the pair of scribing forming line means scribes the first surface of the substrate and the second surface of the substrate.

2. (Original) A substrate cutting system according to claim 1, wherein the substrate supporting means includes:

a substrate supporting device being supporting by the scribing device guide body and moving together with the pair of scribing devices in the Y axial direction; and

a fixing device for fixing the substrate in the X-Y plane.

3. (Original) A substrate cutting system according to claim 2, wherein the substrate supporting device supports the substrate such that the substrate supporting device does not rub the substrate or exert any force on the substrate when the pair of scribing devices and the scribing device guide body move in the Y axial direction.

4. (Original) A substrate cutting system according to claim 2, wherein the substrate supporting device includes:

a first substrate supporting section being provided on one side of the substrate supporting device with respect to a moving direction of the scribing device guide body.

5. (Original) A substrate cutting system according to claim 4, wherein the first substrate supporting section includes a plurality of first substrate supporting units, the plurality of first substrate supporting units moving in parallel along the moving direction of the scribing device guide body, and

the plurality of first substrate supporting units moves together with the scribing device guide body along with the movement of the scribing device guide body.

6. (Original) A substrate cutting system according to claim 5, wherein the first substrate supporting unit includes a substrate supporting means for supporting the substrate.

7. (Original) A substrate cutting system according to claim 6, wherein the substrate supporting section is a plurality of cylindrical rollers.

8. (Original) A substrate cutting system according to claim 7, comprising at least one rotation transmission means for rotating the plurality of cylindrical rollers in accordance with the movement of the scribing device guide body.

9. (Original) A substrate cutting system according to claim 7, comprising a control section for rotating the plurality of cylindrical rollers in accordance with the movement of the scribing device guide body.

10. (Original) A substrate cutting system according to claim 6, wherein the substrate supporting means is a plurality of belts.

11. (Original) A substrate cutting system according to claim 10, comprising at least one rotation transmission means for circling the plurality of belts in accordance with the movement of the scribing device guide body.

12. (Original) A substrate cutting system according to claim 10, comprising a control section for circling the plurality of belts using a motor in accordance with the movement of the scribing device guide body.

13. (Original) A substrate cutting system according to claim 2, wherein the substrate supporting device includes:

a second substrate supporting section being provided on another side of the substrate supporting device with respect to a moving direction of the scribing device guide body.

14. (Original) A substrate cutting system according to claim 13, wherein the second substrate supporting section includes a plurality of second substrate supporting units, the plurality of second substrate supporting units moving in parallel along the moving direction of the scribing device guide body.

15. (Original) A substrate cutting system according to claim 14, wherein the second substrate supporting unit includes a substrate supporting means for supporting the substrate.

16. (Original) A substrate cutting system according to claim 15, wherein the substrate supporting section is a plurality of cylindrical rollers.

17. (Original) A substrate cutting system according to claim 16, comprising at least one rotation transmission means for rotating the plurality of cylindrical rollers in accordance with the movement of the scribing device guide body.

18. (Original) A substrate cutting system according to claim 16, comprising a control section for rotating the plurality of cylindrical rollers in accordance with the movement of the scribing device guide body.

19. (Original) A substrate cutting system according to claim 15, wherein the substrate supporting means is a plurality of belts.

20. (Original) A substrate cutting system according to claim 19, comprising at least one rotation transmission means for circling the plurality of belts in accordance with the movement of the scribing device guide body.

21. (Original) A substrate cutting system according to claim 19, comprising a control section for circling the plurality of belts using a motor in accordance with the movement of the scribing device guide body.

22. (Original) A substrate cutting system according to claim 1, wherein the pair of scribing devices each includes a cutter head for transmitting a pressing force of the scribing forming means onto the substrate using a servo motor.

Claim 23 – 45 (Cancelled)

46. (Original) A substrate cutting system according to claim 10, wherein the plurality of belts is wound around between a frame on a carry-in side of the substrate and a frame on a carry-out side of the substrate, and

the plurality of belts lowers below the scribing device guide body or emerges above the scribing device guide body from under the scribing device guide body while the first substrate supporting section is moving.

47. (Original) A substrate cutting system according to claim 19, wherein the plurality of belts is wound around between a frame on a carry-in side of the substrate and a frame on a carry-out side of the substrate, and

the plurality of belts lowers below the scribing device guide body or emerges above the scribing device guide body from under the scribing device guide body while the second substrate supporting section is moving.

48. (Original) A substrate cutting system according to claim 1, wherein the substrate is a bonded mother substrate for which a pair of mother substrates are bonded to each other.

49. (Original) A substrate manufacturing apparatus, comprising:
a substrate cutting system according to claim 1; and
a chamfering system for chamfering an edge face of a cut substrate,
wherein the substrate cutting system is connected to the chamfering system.

50. (Original) A substrate manufacturing apparatus, comprising:
a substrate cutting system according to claim 1; and
an inspection system for inspecting the function of a cut substrate,
wherein the substrate cutting system is connected to the inspection system.

51. (Original) A substrate manufacturing apparatus according to claim 49, further comprising an inspection system for inspecting the function of the cut substrate.

Claim 52 – 59 (Cancelled)